

TITLE OF INVENTION: MANUFACTURING APPARATUS WITH CLEANING MECHANISM AND CLEANING METHOD

Provided inside a manufacturing apparatus is a cleaning mechanism for making the manufacturing-apparatus interior and the processing space thereof into a cleaner atmosphere than the out-of-apparatus environment. That is, the atmosphere in the apparatus divided by a cabinet (1) from a general environment is circulated through a filter (3) as clean atmosphere by using a fan (2) as power source and a clean air passed through a clean filter (15) from a gas feed pipe (14) is fed to the apparatus interior. According to such an arrangement, since a processing space in the apparatus can be kept to a clean state at all times and this manufacturing apparatus is provided in a general environment, an inexpensive clean space is implementable without need for an enormous investment or maintenance and management cost, unlike clean environmental plant such as general clean rooms or clean spatial passage device. The present invention is thus contributable to a quality improvement and cost reduction of products.

Figure 1.